Amendments to the Claims:

The following listing of claims will replace all prior versions, and listings, of claims in the application:

1. (Previously Amended) A micromachine comprising:

a first microstructured portion; and

a second microstructured portion of a predetermined shape, at least a part of which is formed by mold transfer, the first microstructured portion connected to the second microstructured portion for driving the second microstructured portion to cause substantially all reflected incident light from a light source to travel in a direction almost perpendicular to an area between the first and second microstructured portions.

2. (Previously Amended) The micromachine according to claim 1, said second microstructured portion having a switching function.

3. (Previously Amended) The micromachine according to claim 1, said second microstructured portion performing as an optical switching element.

4. (Previously Amended) The micromachine according to claim 1, said first microstructured portion and said second microstructured portion being arranged in an array.

5. (Previously Amended) The micromachine according to claim 1, further comprising:

a third microstructured portion of a predetermined shape not driven by said first microstructured portion, at least a part of said third microstructured portion which relates to said second microstructured portion being formed by mold transfer.

6. (Previously Amended) The micromachine according to claim 5, one of a predetermined gap and a predetermined step being provided between said second microstructured portion and said third microstructured portion.

7. (Previously Amended) The micromachine according to claim 1, said first microstructured portion being formed by photolithography techniques.

8. (Previously Amended) The micromachine according to claim 1, said second microstructured portion comprising a resin.

9. (Previously Amended) The micromachine according to claim 8, said second microstructured portion comprising a photosetting resin.

10. (Currently Amended) The micromachine according to claim 8, a boundary surface between said first microstructured portion and said second microstructured portion comprising a ~~metallic~~ non-metallic material.

11. (Previously Amended) A micromachine manufacturing method for manufacturing a micromachine, in which a first microstructured portion is operative to drive a second microstructured portion of a predetermined shape, the method comprising:

a first microstructured portion providing step of providing a first microstructured portion; and

a molding step of forming at least a part of said second microstructured portion on said first microstructured portion by mold transfer, after said first microstructured portion is provided so that substantially all reflected incident light from a light source travels in a direction almost perpendicular to an area between the first and second microstructured portions.

12. (Previously Amended) The micromachine manufacturing method according to claim 11, said second microstructured portion having a switching function.

13. (Previously Amended) The micromachine manufacturing method according to claim 11, said second microstructured portion performing as an optical switching element.

14. (Previously Amended) The micromachine manufacturing method according to claim 11, further comprising a plurality of first microstructured portions and a plurality of

second microstructured portions arranged in an array, a part of each of the plurality of second microstructured portions arranged in the array being transferred using a same mold used in said molding step.

15. (Previously Amended) The micromachine manufacturing method according to claim 11, said micromachine comprising a third microstructured portion not driven by said first microstructured portion, at least a part of said third microstructured portion which relates to said second microstructured portion being transferred using a same mold used in said molding step.

16. (Previously Amended) The micromachine manufacturing method according to claim 15, one of a predetermined gap and a predetermined step being formed between said second microstructured portion and said third microstructured portion in said molding step.

17. (Previously Amended) The micromachine manufacturing method according to claim 11, further comprising:

a photolithography step performed before said molding step, said first microstructured portion being formed by photolithography techniques in said photolithography step.

18. (Previously Amended) The micromachine manufacturing method according to claim 17, further comprising:

an etching step of etching a sacrifice layer after said molding step, said sacrifice layer, which is provided around said first microstructured portion, not being etched at said photolithography step.

19. (Previously Amended) The micromachine manufacturing method according to claim 17, no metallic film being formed on a boundary surface, on which said second microstructured portion is stacked, in said photolithography step.

20. (Previously Amended) The micromachine manufacturing method according to claim 11, further comprising:

a sacrifice layer providing step of providing a sacrifice layer around said first microstructured portion before said molding step.

21. (Currently Amended) The micromachine manufacturing method according to claim 11, further comprising:

a planarizing step of planarizing said first microstructured portion and surroundings thereof during or following ~~before~~ said molding step.

22. (Previously Amended) The micromachine manufacturing method according to claim 11, a mold used in said molding step being formed on a silicon substrate by a combination of anisotropic etching and isotropic etching in such a manner so as to have a predetermined shape.

23. (Previously Amended) The micromachine manufacturing method according to claim 11, a mold used in said molding step being adapted to transmit light.

24. (Previously Amended) The micromachine manufacturing method according to claim 11, a mold used in said molding step being a secondary mold obtained by reverse-forming of a first mold.

25. (Previously Amended) The micromachine manufacturing method according to claim 11, said molding step comprising a pressure reducing step of reducing ambient pressure in a state, in which a mold is used, in such a way as to be lower than atmospheric pressure.

26. (Previously Amended) The micromachine manufacturing method according to claim 11, said molding step comprising a pressure reducing step of reducing ambient pressure in a state, in which a mold is used, in such a way as to realize an almost vacuum condition.

27. (Previously Amended) The micromachine manufacturing method according to claim 11, said molding step comprising a second microstructured forming step of forming said second microstructured portion by removing a part of said second microstructured after being molded by mold transfer.